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Substitute for form 1449A/PTO				Complete if Known		
	FORMATIO			APPLICATION NUMBER	10/714,088	
STATEMENT BY APPLICANT				FILING DATE	11/14/2003	
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Sheet	-	-5	12	Group Art Unit	1762	
2liest		of		Examiner Name	Marianne Padgett	
				Attorney Docket Number	P69-11-03	

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Samer nkiels*	Cite No.	U.S. Patent Document Kind Code <sup>2</sup> Number (# known)		Name of Palentee or Applicant of Ched Document	Date of Publication of Cited Occument MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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<i>[///</i>	E2	2004/0007799	A1	Choi et al.	1/15/2004	•
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				Group Art Unit	1762		
Sheet	2	of	2	Examiner Name	Marianne Padgett		
				Attorney Docket Number	P69-11-03		

		- NON PATENT LITERATURE DOCUMENTS	_
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	<b>T</b> <sup>2</sup>
M	E16	APPLICATION NO. 11/101,139, naming Inventors Shackleton et al., entitled System for Controlling a Volume of Material on a Mold, filed 4/7/2005	
MP	E17	APPLICATION NO. 11/101,140, naming inventors McMackin, entitled Method for Fast Filling of Templates for Imprint Lithography Using on Template Dispense, filed 4/7/2005	
		(NERAC.COM RETRO SEARCH, Fluid Dispensing, 6/4/2005	
1 1	E18	? Website notatitle	
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Application Number	10/714,088					
Filing Date	11/14/2003					
First Named Inventor	McMackin et al.					
Group Art Unit	Unassigned 1742					
Examiner Name	Unassigned Palsett					
Attorney Docket Number	P69/MII-29-11-03					

arriner	Cite	U.S. Patent Doo		Name of Patentee or Applicant	Date of Publication of	Pages, Columns, Lines.
itials/	No.'	Number	Kind Code <sup>2</sup> (if known)	of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
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Substitute f	or form 1449A/PTO			Complete if Known		
				Application Number	10/714,088	
INFO	RMATION D	ISC	LOSURE	Filing Date	11/14/2003	
STAT	<b>EMENT BY</b>	APF	PLICANT	First Named Inventor	McMackin et al.	
				Group Art Unit	Unassigned	
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xaminer nitials*	Cite No.1	U.S. Patent Do	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Unes, Where Relevant Passages or Relevant Figures Appear
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STA	STATEMENT BY APPLICANT			First Named Inventor	McMackin et al.	
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Sheet	4	of	6	Attorney Docket Number	P69/MII-29-11-03	

OTHER PRIOR	RART - N	NON PATENT LITERATURE DOCUMENTS	
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Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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<sup>&</sup>lt;sup>1</sup>Unique citation designation number. <sup>2</sup>Applicant is to place a check mark here if English language Translation is attached.

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Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number. Complete if Known Substitute for form 1449B/PTO **Application Number** 10/714,088 **INFORMATION DISCLOSURE Filing Date** 11/14/2003 STATEMENT BY APPLICANT **First Named Inventor** McMackin et al. Group Art Unit Unassigned (use as many sheets as necessary) **Examiner Name Unassigned** 6 Sheet of **Attorney Docket Number** P69/MII-29-11-03

OTHER PRIOR	R ART -	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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		Application Number	10/714,088	
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		First Named Inventor	McMackin et al.	
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Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of Information unless it displays a valid OMB control number Substitute for form 1449A/PTO Complete if Known **APPLICATION NUMBER** 10/714,088 IMPORMATION DISCLOSURE MAR 2 4 2005 PATEMENT BY APPLICANT FILING DATE 11/14/2003 FIRST NAMED McMackin et al. **INVENTOR** Group Art Unit 1762 (use as many sheets as necessary) Padgett, Marianne **Examiner Name** 1 of 6 P69-11-03 Attorney Docket Number

xaminer ilitals*	Cite No.1 Number (if known)		Name of Patentee or Applicant of Cited Document	Dale of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
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				FIRST NAMED INVENTOR	McMackin et al.	
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OTHER PRIO	R ART	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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<sup>\*</sup>Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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				FIRST NAMED INVENTOR	McMackin et al.		
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Sheet	6	of	6	Examiner Name	Padgett, Marianne		
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OTHER PRIOR	R ART -	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
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Attorney Docket Number

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